

P2-001A	Surface Loss Probability of Hydrogen Radical in SiH₄/H₂ Plasma	97
	¹ Y. Abe, ¹ K. Takeda, ¹ K. Ishikawa, ¹ H. Kondo, ^{1,2} M. Sekine, ^{1,2} M. Hori	
	¹ Nagoya University, Japan	
	² JST-CREST, Japan	
P2-002A	Measurement of Optical Properties of Carbon-based Material Using Terahertz Time Domain Spectroscopy	97
	¹ T. Hiraoka, ^{1,2} K. Takeda, ^{1,2} K. Ishikawa, ¹ H. Kondo, ³ M. Ito, ^{1,2} M. Sekine, ^{1,2} M. Hori	
	¹ Nagoya University, Japan	
	² Nagoya University, Japan	
	³ Meijo University, Japan	
P2-003A	Spectroscopic Study on Discharge Plasma in Liquids: (2) Dependence of Temporal Changes of Active Species on Electrodes Distance	98
	Y. Kusama, Y. Someya, H. Yui	
	Tokyo University of Science, Japan	
P2-004A	Experimental Verification of Etching of Spore Forming Bacteria by Surface-wave Excited Oxygen Plasma	98
	A. Tsukasaki, Y. Zhao, A. Ogino, M. Nagatsu	
	Shizuoka University, Japan	
P2-005A	O Radical Measurement in Penicillium Digitatum Inactivation Using Non-equilibrium Atmospheric O₂/Ar Plasma	99
	¹ S. Iseki, ² T. Ohta, ³ M. Ito, ⁴ H. Kano, ¹ K. Takeda, ¹ H. Kondo, ¹ K. Ishikawa, ¹ M. Sekine, ¹ M. Hori	
	¹ Nagoya University, Japan	
	² Wakayama University, Japan	
	³ Meijo University, Japan	
	⁴ NU EcoEngineering CO., LTD., Japan	
P2-006A	Oligomerization of Amino Acid by Pulsed Discharge Plasma in Supercritical Fluids	99
	¹ K. Nagafuchi, ¹ W. Diono, ¹ T. Kiyan, ¹ H. Watanabe, ¹ T. Ihara, ¹ S. Kameda, ¹ T. Furusato, ² H. Akiyama, ¹ M. Sasaki, ² M. Goto	
	¹ Kumamoto University, Japan	
	² Kumamoto University, Japan	
P2-007A	Biomass Degradation by Nano-Pulsed Plasma in Hydrothermal Conditions	100
	¹ W. Diono, ¹ H. Watanabe, ¹ T. Kiyan, ¹ T. Ihara, ¹ H. Akiyama, ¹ M. Sasaki, ² M. Goto	
	¹ Kumamoto University, Japan	
	² Kumamoto University, Japan	

P2-008A	Exhaust Gas Cleaning with Cylinder Shape Dielectric Barrier Discharge	100
	S. Joa, S. Chun, J. Kim, I. Kang, H. Lee Jeju National University, Korea	
P2-009A	Multiple-height Microstructure Fabricated by ICP-RIE and Masking Layers Using Only Photoresists	101
	A. Hikita, T. Iwamoto, S. Kumagai, M. Sasaki Toyota Technological Institute, Japan	
P2-010A	Spectroscopic Study on Discharge Plasma in Liquids: (I) Investigation of Precursor Phenomena for the Discharge	101
	Y. Someya, Y. Kusama, H. Yui Tokyo University of Science, Japan	
P2-011A	Development of Fast Reciprocating Langmuir Probe System for Processing Plasmas	102
	N. Ohno, M. Takagi, S. Kajita Nagoya University, Japan	
P2-012A	Behavior of Metastable He Atom in the Multi-Micro Hollow Cathode Lamp Measured by Laser Absorption Spectroscopy	102
	¹ M. Inoue, ¹ T. Ohta, ¹ T. Kanae, ² M. Ito, ³ K. Yamakawa, ⁴ M. Hori ¹ Wakayama University, Japan ² Meijo University, Japan ³ Katagiri Engineering Co., Ltd., Japan ⁴ Nagoya University, Japan	
P2-013A	Measurement of Electron-Neutral Collision Frequency Using Wave-cut off Method	103
	K. You, B. Na, H. Chang Korea Advanced Institute of Science And Technology, Korea	
P2-014A	Improving the Hydrophilicity of TPU by Helium Atmospheric Plasma	103
	¹ K. Chen, ¹ T. Hung, ¹ S. Liao, ¹ S. Lin, ¹ S. Tsao, ² Y. Ku, ¹ H. Wu ¹ Tatung University, Taiwan ² AMED Co., Ltd, Taiwan	
P2-015A	Argon Plasma Modification of Thermoplastic Polyurethane : A Method Formed Hydrophilic and Hydrophobic Surfaces	104
	¹ K. Chen, ¹ S. Liao, ¹ S. Tsao, ¹ T. Hung, ¹ H. Wu, ² Y. Ku, ¹ S. Lin ¹ Tatung University, Taiwan ² AMED Co., Ltd., Taiwan	

withdrawn

P2-017A	Origin of High-energy X-ray Satellites Spectra in the $L\alpha_1$ Region	105
	S. Pconia Central Arid Zone Research Institute, India	
P2-018A	Electrical Harmonic Sensor Calibration and Plasma Chamber Characterization	105
	R. Tadjine, H. Lahmar, M. Alim, L. Henni Centre de Developpement des Technologies Avancees, Algeria	
P2-019A	Plasma Nano-Technologies for Fabrications of VPH Grating, Quasi-Bragg Grating and Novel Immersion Grating	106
	N. Ebizuka, H. Kondo, K. Ishikawa, M. Hori Nagoya University, Japan	
P2-020A	Radical Flux Modeling and Analysis for Sticking Coefficient Evaluation	106
	¹ A. Malinowski, ¹ M. Hori, ¹ M. Sekine, ¹ K. Ishikawa, ¹ H. Kondo, ¹ H. Yamamoto, ¹ T. Takeuchi, ¹ T. Suzuki, ² A. Jakubowski, ² L. Lukasiak ¹ Nagoya University, Japan ² Warsaw University of Technology, Poland	
P2-021A	Numerical Design of SiO₂ Bridges in Stretchable Thin Film Transistors	107
	Y. Kim, D. Lee, K. Park, N. Lee, J. Ahn Sungkyunkwan University, Korea	
P2-022A	Numerical Simulation of Laser Induced Weakly Ionized Helium Plasma Process by Lattice Boltzmann Method	107
	¹ Z. Xiaobo, ¹ D. Yoshihiro, ² L. Jiping ¹ The University of Tokushima, Japan ² Xi'an Jiaotong University, China	
P2-023A	Sputtering on Carbon Materials by Hydrogen Isotope	108
	¹ S. Yonemura, ¹ S. Saito, ² A. Ito, ² A. Takayama, ¹ S. Kajita, ¹ N. Ohno, ¹ H. Nakamura ¹ Nagoya University, Japan ² National Institute for Fusion Science, Japan	

P2-024A	Numerical Investigation of VHF Plasmas Produced by a Balanced Power Feeding Method	108
	¹ H. Muta, ¹ S. Nishida, ¹ S. Kuribayashi, ² K. Uchino, ² Y. Kawai	
	¹ Gifu University, Japan	
	² Kyushu University, Japan	
P2-025A	Comparison of Plasma Etching between Center and Edge of High Oriented Pyrolytic Graphite Surface by Molecular Dynamics Simulation	109
	¹ A. Ito, ¹ A. Takayama, ² M. Teraoka, ² N. Ohno, ³ S. Kajita, ^{1,2} H. Nakamura	
	¹ National Institute for Fusion Science, Japan	
	² Nagoya University, Japan	
	³ Nagoya University, Japan	
P2-026A	Binary-Collision-Approximation-Based Simulation Study of Carbon Material Exposed to Energetic Hydrogen Isotopes	109
	¹ A. Takayama, ² S. Saito, ¹ A. Ito, ² S. Yonemura, ^{1,2} H. Nakamura	
	¹ National Institute for Fusion Science, Japan	
	² Nagoya University, Japan	
P2-027A	Fully Kinetic Model of Hall Thruster Plasma Dynamics with LRnLA Algorithm	110
	A. Perepelkina, I. Goryachev, V. Levchenko	
	Keldysh Institute of Applied Mathematics Russian Academy of Sciences, Russia	
P2-028A	Influence of the PTFE Ablation on the Interrupting Limit by Electric Arcs in a SF₆ Self-Blast Circuit Breaker	110
	¹ J. Lee, ² J. Heo	
	¹ Gangneung-Wonju National University, Korea	
	² Korea Electric Testing Institute, Korea	
P2-029A	Time Step Acceleration Method for Global Simulation of High Density Plasma Discharges	111
	¹ D. Kwon, ¹ M. Song, ¹ J. Yoon, ² N. Yoon	
	¹ National Fusion Research Institute, Korea	
	² Chungbuk National University, Korea	
P2-030B	Structural Properties of w-Sc_xAl_{1-x}N Thin Films Deposited through Dual Reactive DC Magnetron Sputtering	111
	A. Zukauskaitė, G. Wingqvist, J. Palisaitis, J. Birch, L. Hultman	
	Linköping University, Sweden	
P2-031B	Selective Growth of Nano Scale GaN on Vertex of GaN Pyramids	112
	D. Jo, J. Ok, H. Jeon, A. Lee, K. Lee, K. Kim, H. Ahn, M. Yang	
	Korea Maritime University, Korea	

P2-032B	Effect of Crystallography-Etched Facets of Patterned Sapphire Substrates for GaN-Based LEDs	112
	¹ T. Tsai, ¹ W. Lin, ¹ M. Hung, ² R. Horng, ¹ D. Wu	
	¹ National Chung Hsing University, Taiwan	
	² National Cheng Kung University, Taiwan	
P2-033B	Controlled Surface and Anisotropy Growth of <i>a</i>-plane GaN Structures on the <i>r</i>-plane Sapphire by SAG Technique	113
	B. Kang, K. Song, D. Yoon	
	Sungkyunkwan University, Korea	
P2-034B	Crystallographic Characterization of GaN Nanorods Grown on a Zr Buffer Layer	113
	¹ M. Kim, ¹ M. Shin, ¹ Y. Choi, ¹ H. Jeon, ¹ H. Ahn, ¹ S. Yi, ² S. Choi, ² S. Lee, ³ Y. Yu, ⁴ N. Sawaki	
	¹ Korea Maritime University, Korea	
	² Korea Basic Science Institute, Daegu Branch, Korea	
	³ Pukyong National University, Korea	
	⁴ Aichi Institute of Technology, Japan	
P2-035B	MOVPE Growth and Characterization of InAlGaN and Blue Light Emitting Diodes with InAlGaN/GaN Multi-layer Barrier	114
	¹ J. Kim, ¹ K. Song, ¹ S. Bae, ² D. Lee, ² J. Yu, ¹ C. Shin, ¹ C. Ko	
	¹ Korea Advanced Nano Fab Center, Korea	
	² Kyung Hee University, Korea	
P2-036B	Investigation of Optimal Growth Conditions and Characterization of GaN Nanorods Using HVPE	114
	¹ M. Shin, ¹ M. Kim, ¹ Y. Choi, ¹ H. Jeon, ¹ H. Ahn, ¹ S. Yi, ² Y. Huh, ³ Y. Yu, ⁴ N. Sawaki	
	¹ Korea Maritime University, Korea	
	² Research Institute of Industrial Science and Technology, Korea	
	³ Pukyong National University, Korea	
	⁴ Aichi Institute of Technology, Japan	
P2-037B	Photoluminescence Study of Plasma-Induced Damages in GaN	115
	N. Ito, J. Gao, Y. Nakano, K. Nakamura, H. Sugai	
	Chubu University, Japan	
P2-038B	Development of Radical Beam Monitoring Techniques in RF-MBE Growth of InN	115
	¹ T. Yamaguchi, ¹ T. Fujishima, ¹ T. Araki, ² E. Yoon, ^{1,2} Y. Nanishi	
	¹ Ritsumeikan University, Japan	
	² Seoul National University, Korea	

P2-039B	Plasma MBE Solution Growth of InGaN Nano Structures on SiO₂	116
	M. Einav Mosaic Crystals Ltd, State of Israel	
P2-040B	Effect of Back and Front Side Proton Irradiations onto AlGaIn/GaN HEMTs on Si Substrate	116
	¹ H. Kim, ² F. Ren, ³ S. Pearton, ¹ J. Kim ¹ Korea University, Korea ² University of Florida, USA	
P2-041B	TEM Analyses of High-Quality GaN Grown on (111)Si using an AlInN Intermediate Layer	117
	¹ N. Sawaki, ¹ S. Kawakita, ¹ H. Iwata, ² M. Irie, ² Y. Honda, ² M. Yamaguchi, ² H. Amano ¹ Aichi Institute of Technology, Japan ² Nagoya University, Japan	
P2-042B	Characterization of pn Junctions Fabricated on ICP-etched n-GaN by C-V and DLTS Measurements	117
	¹ S. Yamaguchi, ¹ Y. Tokuda, ² H. Ueda, ² T. Uesugi, ² T. Kachi ¹ Aichi Institute of Technology, Japan ² Toyota Central R&D Labs. Inc., Japan	
P2-043B	Electrical Properties of Cr-N Films Deposited by Sputtering: Application to Cryogenic Temperature Sensors	118
	¹ K. Satoh, ¹ Y. Kakehi, ¹ M. Uno, ¹ Y. Sakurai, ² T. Yotsuya, ² T. Ishida ¹ Technology Research Institute of Osaka Prefecture, Japan ² Osaka Prefecture University, Japan	
P2-044B	Growth and Surface Characterization of Magnetron Sputtered Zinc Nitride Thin Films	118
	¹ J. Khoshman, ² R. Kirste, ² N. Peica, ³ B. Bastek, ⁴ M. Kordesch, ² A. Hoffman ¹ Al-Hussein Bin Talal University, Jordan ² Technische University Berlin, Germany ³ Otto-von-Guericke-University, Germany ⁴ Ohio University, USA	
P2-045C	Preparation and Properties of SPEEK Nanofibrous Ion Exchange Membrane for PEMFC	119
	T. Hwang, E. Choi, Y. Baek, J. Jung, W. Jung, J. Koo Chungnam National University, Korea	

P2-046C	<i>In Vitro</i> Evaluation of the Anti-Cancer Effects of Nitrogen-Plasma Surface Treatment of TiO₂ Nanoparticle on Oral Squamous Cell Carcinoma Cell Lines	119
	K. Lee, Y. Ko, B. Kim Chosun University, Korea	
P2-047C	Effect of Grooving Pitch on the Block-tearing Caused by FIB Assisted Hydrogen Exfoliation	120
	H. Iwata, M. Takagi, Y. Tokuda Aichi Institute of Technology, Japan	
P2-048C	The Characterization of Mg Contained Amorphous Zinc Tin Oxide Thin Film Transistors by Solution Process	120
	J. Lee, C. Jung, M. Choi, D. Yoon Sungkyunkwan University, Korea	
P2-049C	Preparation of NO High Selective Co(III) Complex and the Self-Assembled Modification on Electrode	121
	D. Tsurudome, T. Yano, T. Inomata, Y. Funahashi, T. Ozawa, H. Masuda Nagoya Institute of Technology, Japan	
P2-050C	Preparation and Characterization of PLLA/Chitosan Blend Membranes for Guided Bone Regeneration	121
	J. Byeon, J. Son, S. Jin, Z. Piao, S. Lee, E. Jang, S. Kim Chosun University, Korea	
P2-051C	The Effects of the Surface Parameters: Nano Topography and Energy of Oxide Coatings on Cell Adhesion Potential <i>in vitro</i> Tests	122
	¹ A. Zykova, ² V. Safonov, ³ J. Smolik, ³ R. Rogowska, ⁴ V. Lukyanchenko, ⁴ M. Maliasova, ⁵ O. Virva ¹ Institute of Surface Engineering, Ukraine ² National Science Centre "Kharkov Institute of Physics and Technology", Ukraine ³ Institute for Sustainable Technologies, National Research Institute, Poland ⁴ Inmasters Ltd, Ukraine ⁵ Sitenko Institute Spine and Joint Pathology, AMS, Ukraine	
P2-052C	Complementary Split Ring Resonators at Near-infrared Frequency	122
	X. Xia, Z. Liu, H. Yang, J. Li, C. Gu Institute of Physics, CAS, China	
P2-053C	Formation of Pt-germanide from Pt/a-Ge:H by Remote Hydrogen Plasma Exposure	123
	¹ K. Makihara, ¹ T. Matsumoto, ¹ T. Fujioka, ¹ M. Ikeda, ² S. Miyazaki ¹ Hiroshima University, Japan ² Nagoya University, Japan	

P2-054C	Effect on Optical Property by Formation of GaN Nanocolumns by Inductively Coupled Plasmas	123
	S. Yang, D. Lee, J. Kim, J. Kim, J. Lee Suncheon National University, Korea	
P2-055C	Fabrication of Graphene-Based Electrochemical Capacitor	124
	C. Hsieh, J. Lin, S. Hsu, Y. Che Yuan Ze University, Taiwan	
P2-056C	Plasma-induced Silane Coupling Agent Grafting on the Surface of Al(OH)₃ Powder	124
	^{1,2} Q. Ou, ¹ L. He, ¹ Z. Wu, ¹ H. Gao, ¹ Z. Li, ¹ W. Cheng, ¹ Z. He, ^{1,2} R. Liang ¹ Fudan University, China ² Engineering Research Center of Advanced Lighting Technology, China	
P2-057C	Infrared Radiation from Nanostructured Tungsten	125
	S. Kajita, T. Yokochi, N. Ohno Nagoya University, Japan	
P2-058C	Preparation and Characterization of Hydrophilized Chitosan/Gelatin Porous Scaffolds by Plasma Polymerization	125
	B. Kim, Y. Ko, K. Lee, H. Seo, J. Shim, B. Kim Chosun University, Korea	
P2-059C	Effects of Plasma treated TiO₂ Nano-mesh Surface on Focal Adhesion by Osteoblast Cells in vitro	126
	Y. Hwang, Y. Ko, K. Lee, J. Shim, B. Kim, M. Jeong Chosun University, Korea	
P2-060C	Electrochemical Aptasensor Based on Plasma-Treated CNT Film for Monitoring Thrombin	126
	¹ J. Lee, ¹ J. Jin, ² S. Kim, ¹ N. Min ¹ Korea University, Korea ² Korea University, Korea	
P2-061C	Ion Implantation of Coatings Deposited by PVD and IBAD	127
	B. Skoric, D. Kakas, A. Miletic, M. Gostimirovic University of Novi Sad, Serbia	
P2-062C	Study on Surface Modification of PEN Film by Remote Ar Microplasma	127
	A. Umeda, M. Blajan, K. Shimizu Shizuoka University, Japan	

P2-063C	Influence of the Pulse Rising Time on the Plasma Irradiation Effect of Polycarbonate	128
	¹ T. Yabuuchi, ¹ S. Yasui, ² M. Noda ¹ Nagoya Institute of Technology, Japan ² Chubu University, Japan	
P2-064C	Study on Difference between Static and Dynamic Friction Coefficients of DLC Film Deposited by Surface Wave-Excited Plasma CVD	128
	A. Hanihara, H. Kousaka, T. Tokoroyama, N. Umehara Nagoya University, Japan	
P2-065C	Adhesion and Proliferation of Human Gingival Fibroblast on Nitrogen-Plasma Treated on Anodized Ti Surface after Visible Light Treatment	129
	J. Shim, K. Lee, Y. Ko, B. Kim Chosun University, Korea	
P2-066C	Sol-gel Nano-Coating on Stainless Steel	129
	K. Shibagaki, T. Ban, Y. Ohya Gifu University, Japan	
P2-067C	Surface Modification of SCM415 by the Ion Bombardment Process of Filtered Cathodic Vacuum Arc Plasma	130
	D. Kim, S. Lee, J. Kim Korea Institute of Materials Science, Korea	
P2-068C	Low-Temperature Fabrication of Ge Nanostructures by Ion Irradiation with a Simultaneous Metal Supply: Effect of Supplied Metal Species	130
	¹ A. Miyawaki, ¹ T. Hayashi, ² T. Tokunaga, ¹ A. Hayashi, ¹ Y. Hayashi, ² M. Tanemura ¹ Nagoya Institute of Technology, Japan ² Nagoya University, Japan	
P2-069C	Development and Application of Electron Beam-Excited Plasma System using Hollow Cathode Electron Source	131
	¹ K. Yamakawa, ¹ S. Den, ¹ S. Takahashi, ¹ H. Yamamoto, ² M. Hori, ² H. Kondo ¹ Katagiri Engineering Co., Ltd., Japan ² Nagoya University, Japan	
P2-070C	Inner Surface Treatments of Long Polymer Tubes using Tubular Low-Pressure Plasma	131
	S. Takashima, M. Ito, S. Sawada Plasma Center for Industrial Applications (PLACIA), Japan	

P2-071C	Epitaxial Indium Tin Oxide Film Deposited on Sapphire Substrate by Solid-Source ECR Plasma	132
	^{1,3} S. Kaneko, ² H. Torii, ¹ K. Akiyama, ³ M. Yoshimoto, ² T. Amazawa ¹ Kanagawa Prefectural Government, Japan ² MES-AFTY Corp., Japan ³ Tokyo Institute of Technology, Japan	
P2-072C	Correlation between Mass Density and Mechanical Properties of DLC Films Deposited by Different Coating Processes	132
	¹ T. Horiuchi, ¹ S. Kaneko, ¹ K. Yoshida, ¹ C. Kato, ¹ M. Kano, ¹ M. Kumagai, ² T. Suzuki ¹ Kanagawa Industrial Technology Center, Japan ² Keio University, Japan	
P2-074C	Fabrication of P-type Zinc Oxide Thin Films by Plasma Immersion Ion Implantation	133
	R. Liang, S. Zhang, Q. Ou, Z. Li, L. He, X. Chang, Z. Wu, Z. He, H. Gao Fudan University, China	
P2-075C	Epoxy Resin Surfaces Functionalization Using Atmospheric Pressure Plasma Jet Treatment and its Simulation Study	133
	^{1,2,3} W. Sangprasert, ^{1,2,3} P. Nimmanpipug, ^{1,2,3} V. Sanghirun Lee, ^{3,4} D. Boonyawan, ⁵ P. Yavirach ¹ Chiang Mai University, Thailand ² Chiang Mai University, Thailand ³ Thailand Center of Excellence In Physics, CHE, Thailand ⁴ Chiang Mai University, Thailand ⁵ Chiang Mai University, Thailand	
P2-076C	Air-Oxidation of Nano-Multilayered CrAlSiMgN Thin Films between 600 and 900 °C	134
	¹ D. Lee, ¹ T. Nguyen, ² S. Kim ¹ Sungkyunkwan University, Korea ² University of Ulsan, Korea	
P2-077C	Nitrides and Oxides Synthesis in Electron Beam Plasma	134
	M. Vasiliev, S. Lysenko, T. Vasilieva Moscow Institute of Physics and Technology, Russia	
P2-078C	Nitrogen-containing Plasma on Polymeric Culture Dish for Cell Adhesion and Proliferation	135
	¹ S. Tunma, ² K. Inthanon, ² W. Wongkham, ² D. Boonyawan ¹ THEP Center, Thailand ² Chiang Mai University, Thailand	

P2-079C	Immobilization of Diiron Complexes on Electrode Surfaces for Four-Electron Reduction of O₂	135
	T. Kitagawa, T. Inomata, Y. Funahashi, T. Ozawa, H. Masuda Nagoya Institute of Technology, Japan	
P2-080C	Application of Inductively Coupled Plasma to Ultra-superhard Nanocrystalline TiN Coatings	136
	S. Chun Mokpo National University, Korea	
P2-081C	High-Temperature Oxidation of Nano-multilayered AlTiSiN Thin Films in Air	136
	¹ D. Lee, ¹ T. Nguyen, ² S. Kim ¹ Sungkyunkwan University, Korea ² University of Ulsan, Korea	
P2-082C	Development of Artificial Siderophore-Modified Probe for Microbial Cell Surface Observation System	137
	J. Ito, Y. Kume, T. Inomata, Y. Funahashi, T. Ozawa, H. Masuda Nagoya Institute of Technology, Japan	
P2-083C	Influence of Electrical Wave Forms on the Surface Modification of AZ91 Alloy Processed by Plasma Electrolytic Oxidation	137
	¹ K. Lee, ¹ I. Hwang, ¹ B. Lee, ² Y. Ko, ¹ D. Shin ¹ Hanyang University, Korea ² Yeungnam University, Korea	
P2-084C	Surface Modification of Tapioca Starch by Atmospheric Argon Plasma	138
	P. Deeyai, S. Dangtip, M. Suphantharika Mahidol University, Thailand	

- P2-085A-LN **Globel Simulation of C4F6 Discharge in a Solenoidal-type Inductively Coupled Plasma Source**
¹M. Song, ¹J. Yoon, ¹D. Kwon, ¹W. Jhang, ¹J. Park, ¹S. Hwang, ¹Y. Kang, ²Y. Im
¹National Fusion Research Institute, Korea
²Chonbuk National University, Korea
- P2-086A-LN **The Study on Arc Constriction Mechanism with Axial Magnetic Field in High-Current Vacuum Arc**
¹J. Lee, ²Y. Kim
¹Gangneung-Wonju National University, Korea
²Sungkyunkwan University, Korea
- P2-087B-LN **Low Temperature GaN Epitaxial Growth Assisted by Hyperthermal Neutral Beams**
¹S. Yoo, ^{1,2}S. Kim, ¹D. Ku, ¹I. Yu, ²M. Cho
¹National Fusion Research Institute, Korea
²Pohang University of Science and Technology, Korea
- P2-088B-LN **Gallium Nitride Film Growth using a Plasma Based Migration Enhanced Afterglow (MEAglow) CVD System**
^{1,2}K. Butcher, ^{1,2}B. Kemp, ^{1,2}I. Hristov, ¹P. Terziyska, ¹P. Binsted, ⁰D. Alexandrov
¹Lakehead University, Canada
²Meaglow Ltd, Canada
- P2-089C-LN **Synthesis of Zn-doped CuO Nanowires by Thermal Oxidation**
¹S. Chen, ¹C. Hsu, ²T. Tsai,
¹National University of Tainan, Taiwan
²National Cheng Kung University, Taiwan
- P2-090C-LN **Structural Characteristics of Zinc Oxide Films Treated in Ar/O₂ Atmosphere Using Microwave Plasma Jet Sintering System**
¹C. Su, ¹C. Huang
¹National Taipei University of Technology, Taiwan

P2-091C-LN **Etching of Diamond with Excess Boron Dopant Atoms Leads to Vertically Aligned Diamond Whiskers**

¹C. Terashima, ²A. Fujishima, ³N. Saito, ^{1,3}O. Takai

¹Nagoya University, Japan

²Tokyo University of Science, Japan

³Nagoya University, Japan

P2-092C0LN **Preparation and Characterization of Nanostructured ZnO Films on Different Substrates by Hydrothermal Method**

¹S. Venkatachalam, ¹H. Nanjo, ¹K. Kawasaki, ¹Y. Wakui, ¹H. Hayashi, ¹T. Ebina

¹AIST, Japan